

Fig. 1B (Prior Art)

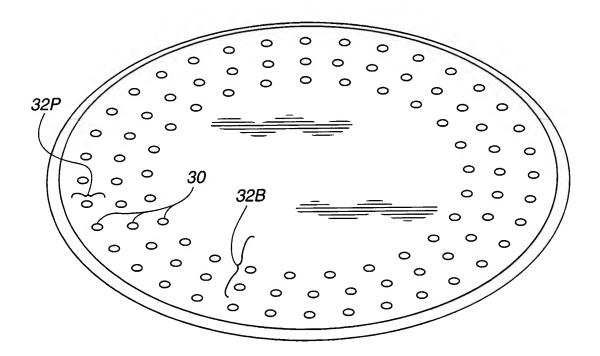
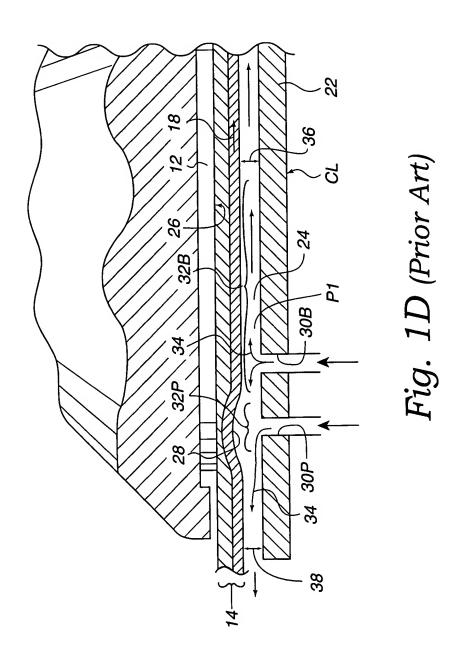


Fig. 1C (Prior Art)



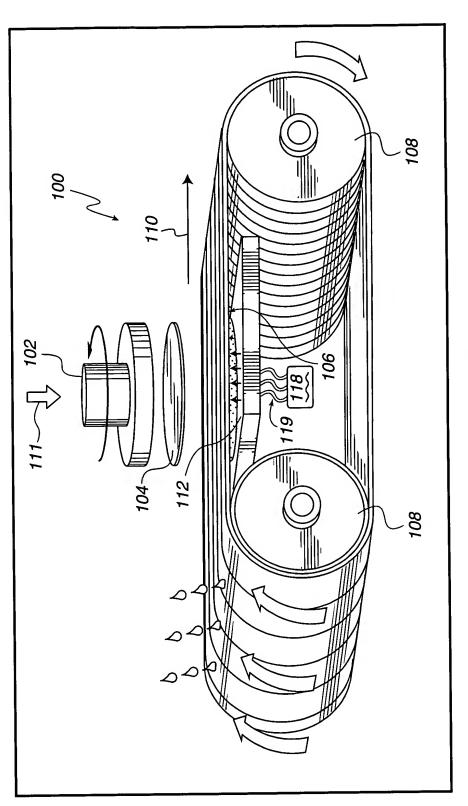
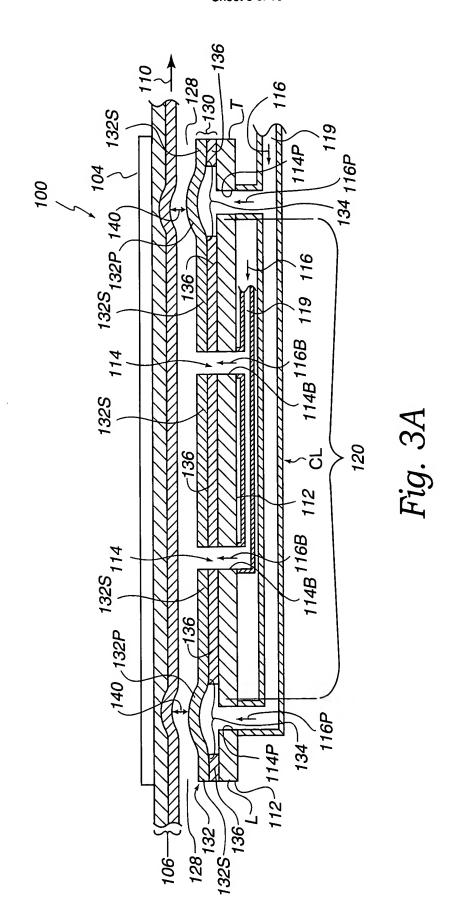
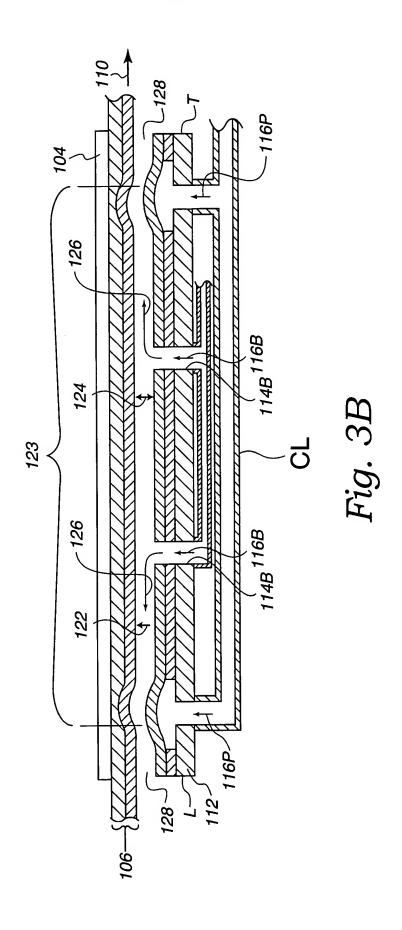


Fig. 2





PLATEN WITH DIAPHRAGM AND METHOD FOR OPTIMIZING WAFER POLISHING A.Kiermasz et al.: LAM2P421 Sheet 7 of 13

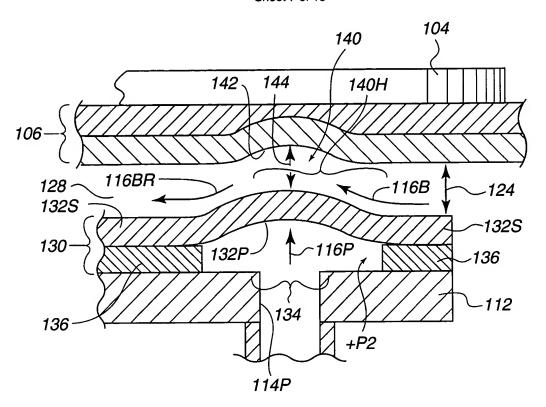
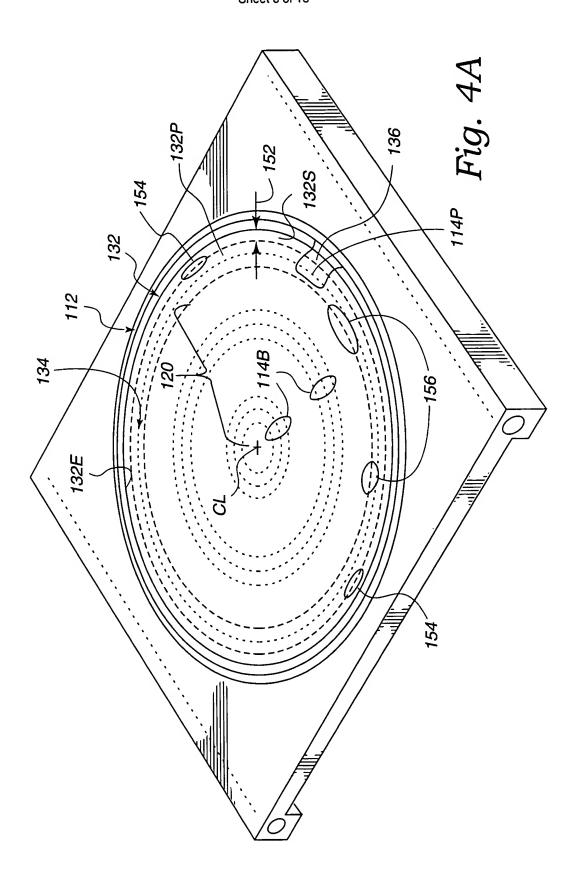
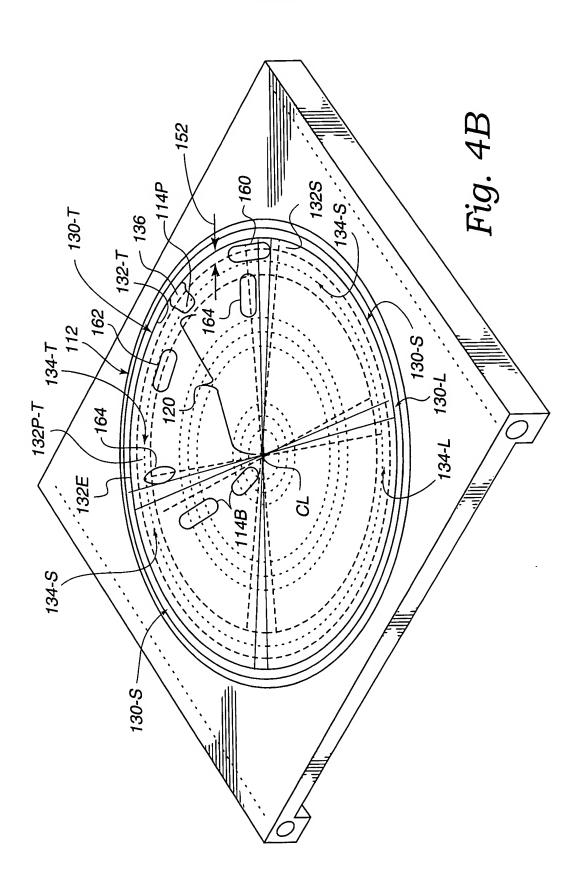
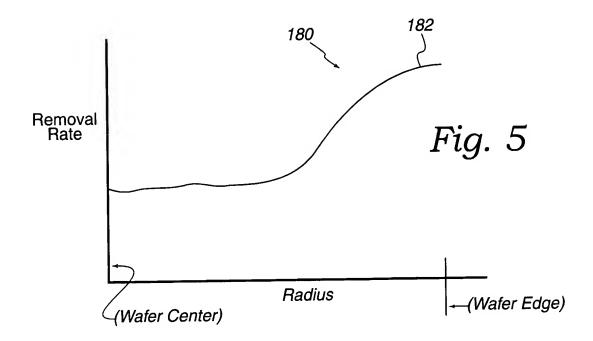


Fig. 3C 104 140 -140L 142 -144 116B 116BR -124 128 --132S 136 132P² 134 -112 114P-Fig. 3D







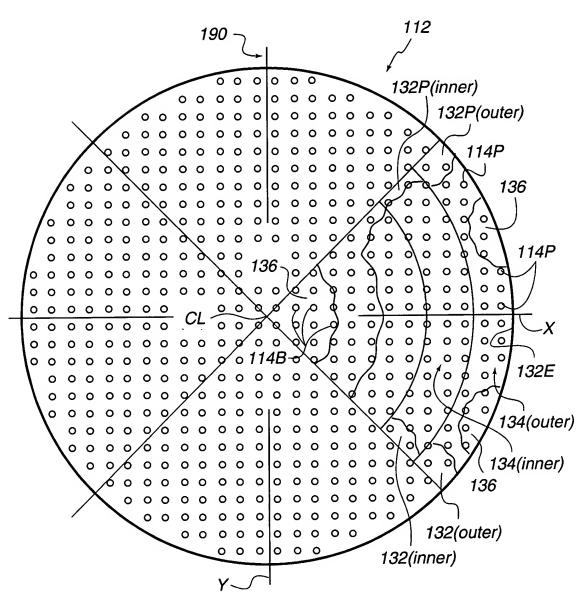


Fig. 6

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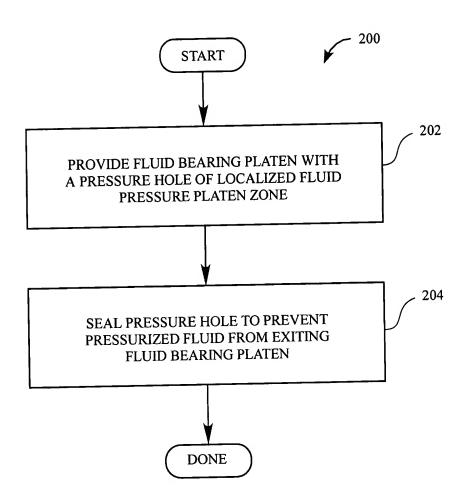


Fig. 7

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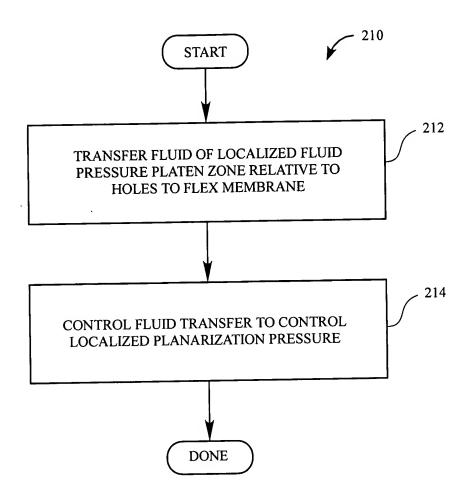


Fig. 8